MATERIALS SYNTHESIS

Bulk Materials

- Solid state synthesis "shake & bake"
- Chemical vapor transport
- Sol Gel Synthesis
- Melt growth

Thin Films

- Chemical Vapor Deposition
- Laser Ablation
- Sputtering
- Molecular Beam Epitaxy

Just a few of the huge number of different methods!

Nanomaterials

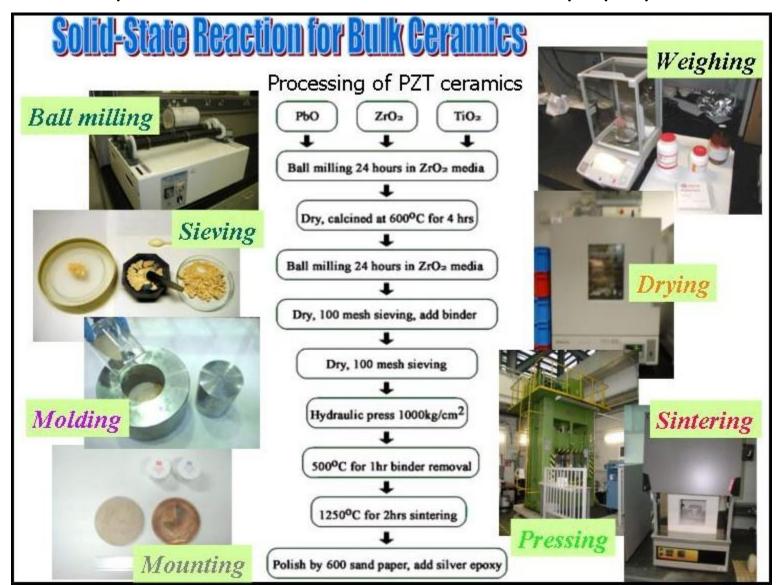
- Nanocrystals
- Carbon Nanotubes
- Nanowires

Reading: West 4

SOLID STATE SYNTHESIS

Mix starting materials, heat, compress presto!

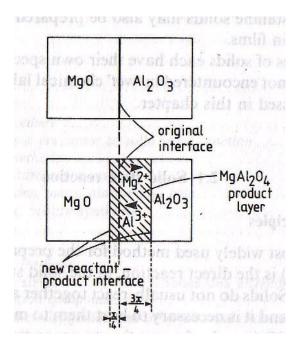
· Historically the most common method to make polycrystalline samples.



SOLID STATE SYNTHESIS

relies on enhanced solid-state diffusion at high temps.

$$4MgO + 4Al_2O_3 \rightarrow 4MgAl_2O_4$$



at MgO/MgAl₂O₄ interface:

$$2AI^{3+} - 3Mg^{2+} + 4MgO \rightarrow MgAl_2O_4$$

at $Al_2O_3/MgAl_2O_4$ interface:

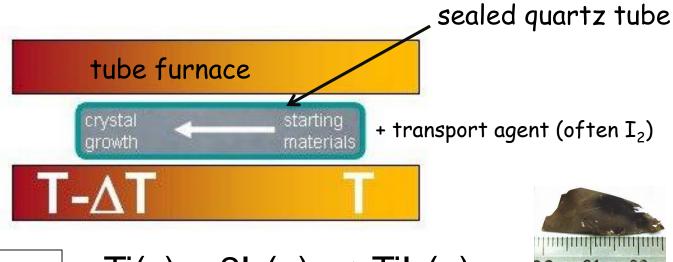
$$3Mg^{2+} - 2Al^{3+} + 4Al_2O_3 \rightarrow 3MgAl_2O_4$$

- factors:
- 1. area of contact between the reacting solids
- 2. the rate of nucleation of the product phase
- 3. the rates of ion diffusion through the various phases

CHEMICAL VAPOR TRANSPORT (CVT)

Crystal growth by the thermal transport of volatile compounds generated from nonvolatile elements or compounds.

Popularized by Schafer (1971).



Ti + S₂
$$\rightarrow$$
 TiS₂ Ti(s) + 2I₂(g) \rightleftharpoons TiI₄(g) $\stackrel{20-21-22}{=}$ TiI₄(g) + S₂(g) \rightarrow TiS₂(s) + 2I₂(g)

- 1. synthesis of new compounds
- 2. growth of large single crystals
- 3. purification of compounds

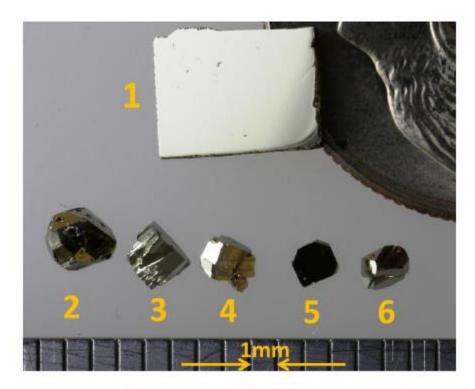
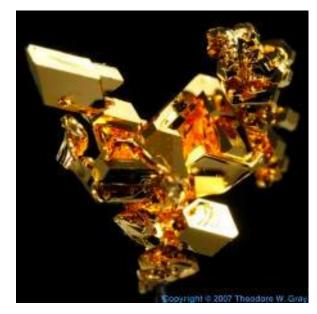


Figure 1: Pyrite crystals used in preliminary studies: Slice from natural crystal, polished to atomic flatness (1), synthetic crystals from flux growth (2) and chemical vapor transport (3-6).





Au (using I_2)

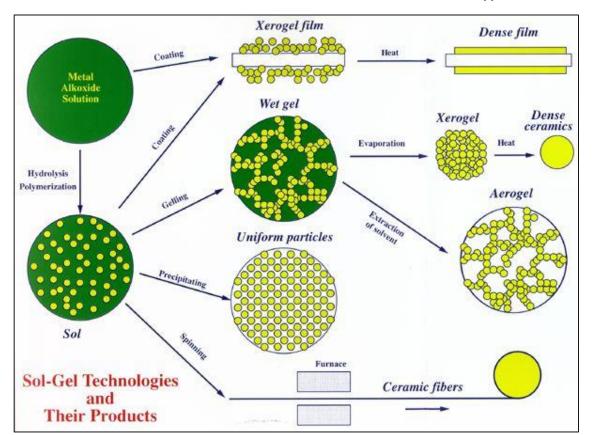
Typical transporting agents include: I_2 , Br_2 , Cl_2 , HCl, NH_4Cl , H_2 , H_2O , $TeCl_4$, $AlCl_3$, CO, S_2

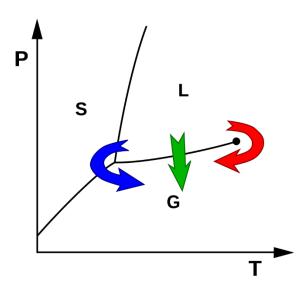
SOL GEL (solution-gelation) PROCESS

Low-temp, solution phase method that uses hydrolysis and polycondensation reactions to form an inorganic network solid.

• makes ceramic and glassy materials, usually from $M(OR)_x$ solutions.

M-OR +
$$H_2O \longrightarrow M$$
-OH + ROH (hydrolysis)
M-OR + M-OH \longrightarrow [M-O-M]_n + ROH (condensation)





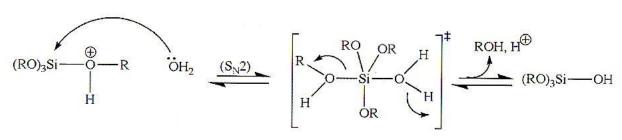
Green: normal drying Blue: freeze drying

Red: supercritical drying

SiO₂ from tetraethyl orthosilicate (TEOS)

acid-catalyzed reaction mechanism:

$$(RO)_3Si$$
 $OR + H^{\bigoplus}$ $fast$ $(RO)_3Si$ O R

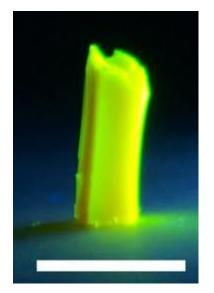


$$(RO)_{3}Si \longrightarrow OH$$

$$+ \underbrace{Slow}_{(RO)_{3}}Si \longrightarrow O \longrightarrow R$$

$$(RO)_{3}Si \longrightarrow O \longrightarrow R$$

380



xerogel containing CdSe/CdS quantum dots



aerogel

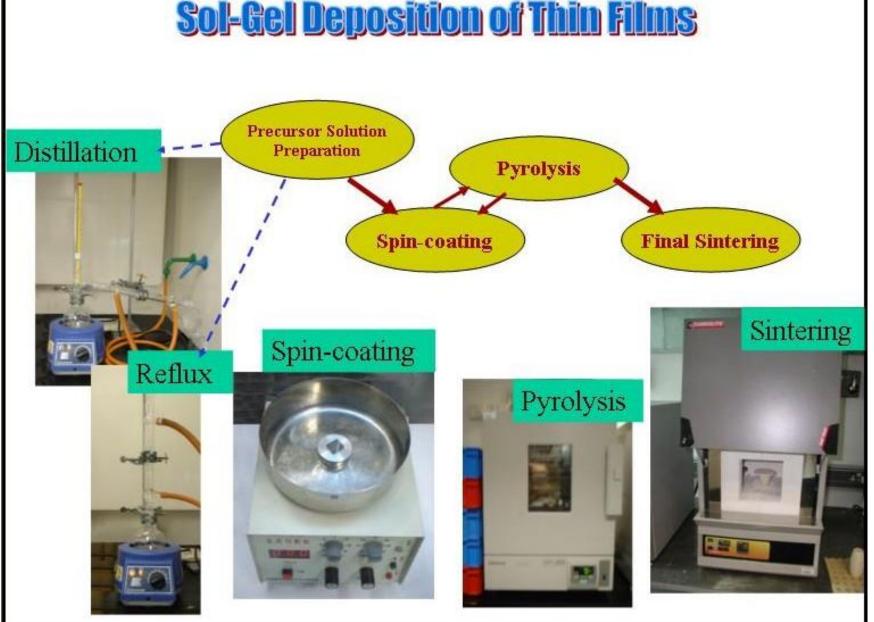








Sol-Gel Deposition of Thin Films



MELT GROWTH

Crystallization from the liquid, without solvent.

 \rightarrow Production of semiconductor grade silicon from silica (sand).

The Siemens process

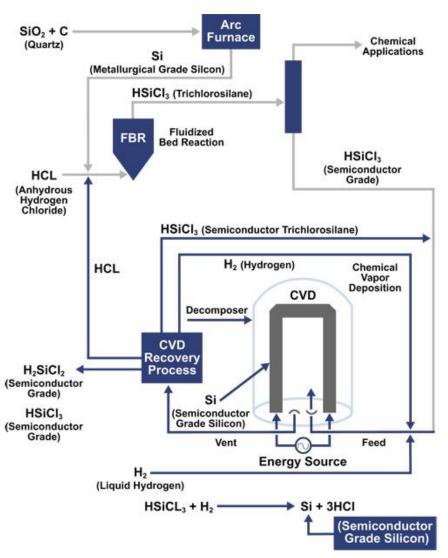
$$SiO_2 + 2C \xrightarrow{2250^{\circ}C} Si + 2CO$$
98-99%
(metallurgical grade)

Si + 3HCl
$$\xrightarrow{300^{\circ}\text{C}}$$
 SiHCl₃ + H₂

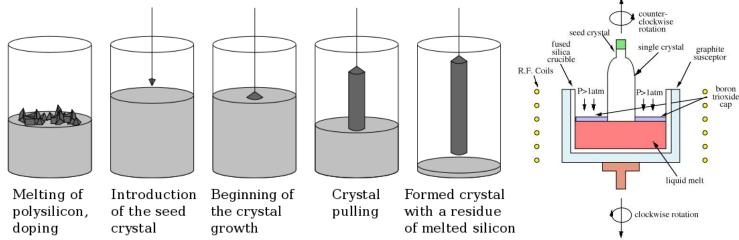
$$2SiHCl_3 \xrightarrow{1150^{\circ}C} Si + 2HCl + SiCl_4$$

99.9999999999999%
(semiconductor grade)

Siemens process makes polycrystalline SG-Si

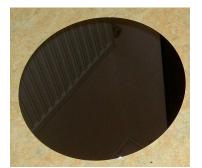


Czochralski (cho-HRAL-ski) process makes single crystal ingots from polycrystalline SG-Si



- good for making doped Si
- suffers from O and C impurities from the crucible







CZ-Si 384

Bridgman-Stockbarger and float zone techniques

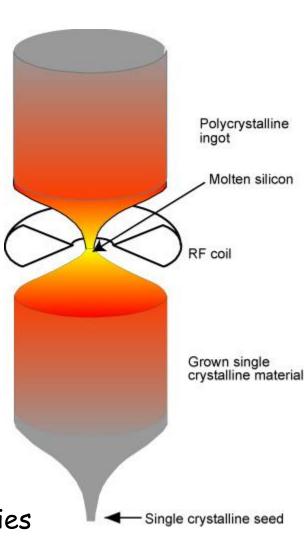
makes use of the greater solubility of impurities in the melt than the crystal



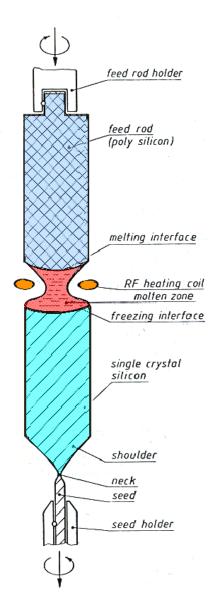
• melt touches nothing

 \rightarrow fewer O and C impurities

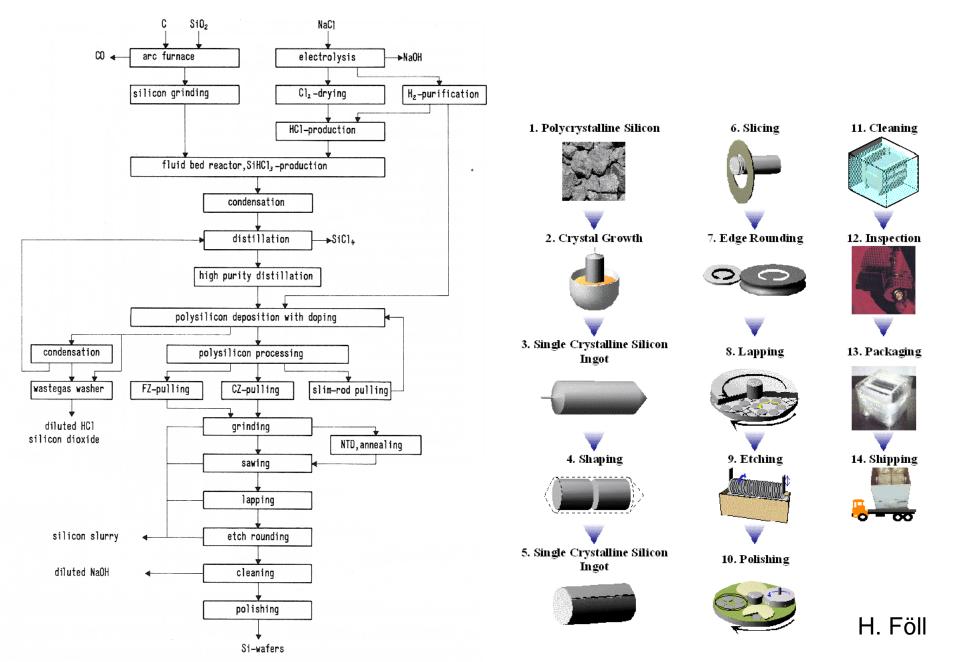
FZ ingots limited to ~200 mm



Float-zone pulling



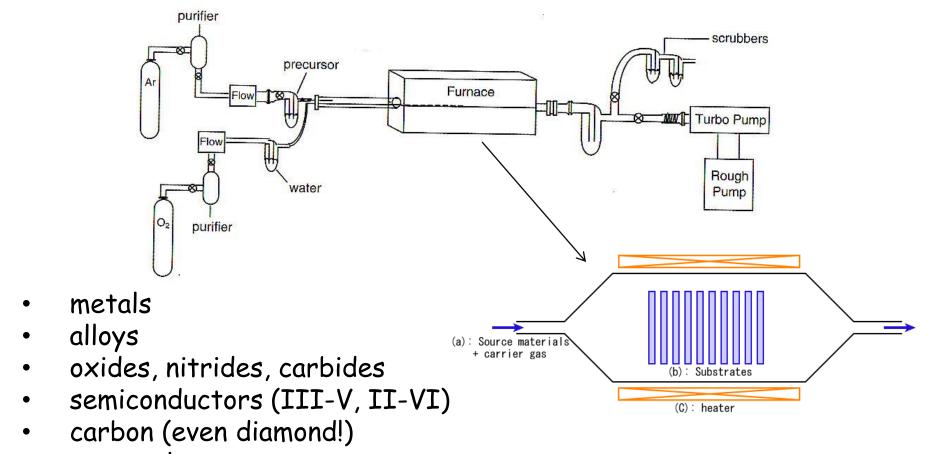
SAND TO SILICON



CHEMICAL VAPOR DEPOSITION (CVD)

Reactive thermolysis of volatile molecular precursors to grow a thin film layer.

a hot wall low-pressure CVD (LP-CVD) reactor:



many others

TYPES OF CVD

by reactor type:

- hot wall

cold wall by pressure:

- atmospheric pressure CVD (AP-CVD)
- LP-CVD >10-6 Torr
- ultrahigh vacuum (UHV-CVD) <10-8 Torr

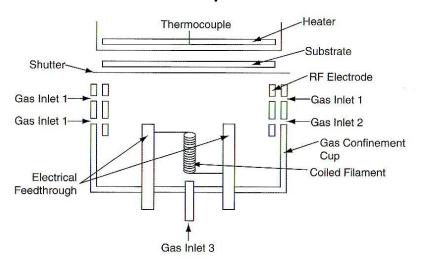
by precursor degradation method:

- plasma enhanced CVD (PE-CVD)
- laser-assisted CVD (LA-CVD)
- hot-wire CVD (HW-CVD)

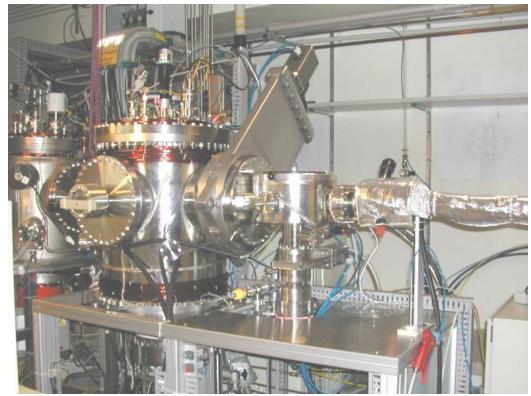
plasma system (a): substrate (b): plasma (e): electrodes (d): to pump

hot wire system

(c): source gas carrier gas

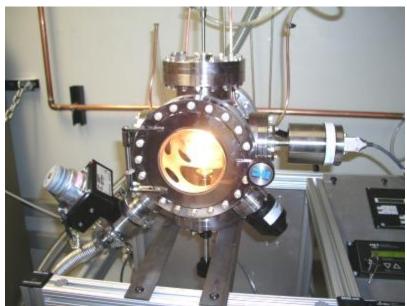


PE-CVD for SiGe growth



Danny Chrastina

Hot wire CVD for a-Si



EXAMPLES

polysilicon

$$SiH_4 \rightarrow Si + 2H_2$$
 LP-CVD, 600-1000°C, 10-100s of nm min⁻¹

silicon nitride (Si₃N₄)

$$3SiH_4 + 4NH_3 \rightarrow Si_3N_4 + 12H_2$$
 LP-CVD, 600-800°C, 10s of nm min⁻¹

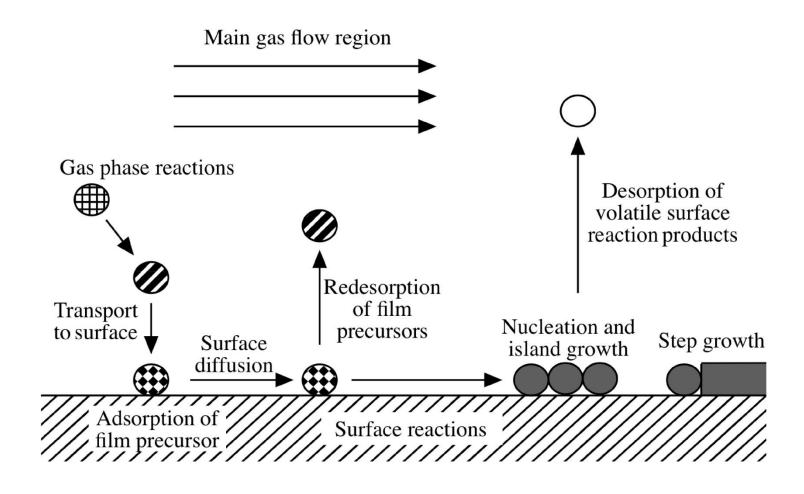
gallium arsenide (GaAs)

$$Ga(Me)_3 + AsH_3 \rightarrow GaAs + 3CH_4 \quad LP-CVD, 400-800^{\circ}C \text{ in } H_2 \text{ carrier gas}$$

example of metal organic CVD (MO-CVD)

IMPORTANT STEPS IN CVD

physisorption, chemisorption → reaction → nucleation → growth



GaAs: Overall Reaction Pathway (350-500°C)

$$Ga(CH_3)_3 \rightarrow Ga(CH_3)_2 + CH_3$$
 (low energy, gas phase)

$$Ga(CH_3)_2 \rightarrow GaCH_3 + CH_3$$
 (gas/surface)

 $GaCH_3 \rightarrow Ga + CH_3$ (surface)

 $Ga(CH_3)_2 \rightarrow Ga + H_3C-CH_3$ (reductive elimination)

$$AsH_3 \rightarrow AsH_2$$

$$AsH_2 \rightarrow HAs + H \qquad (surface)$$

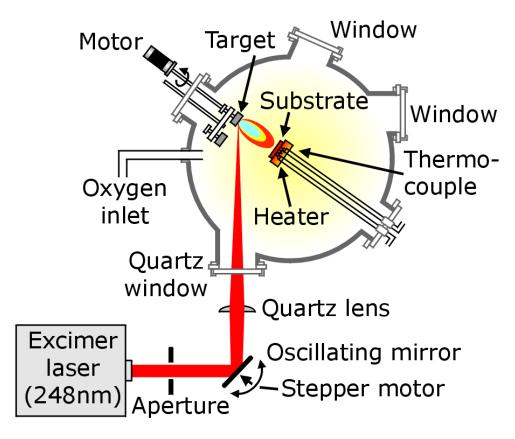
$$HAs \rightarrow As + H \qquad (surface)$$

$$H + CH_3 \rightarrow CH_4$$
 (surface)

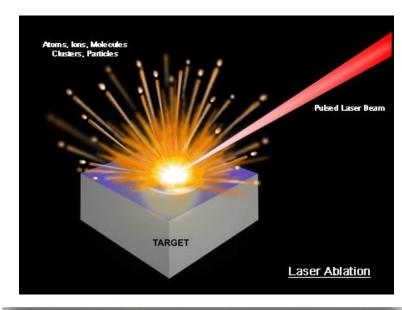
PULSED LASER DEPOSITION (PLD)

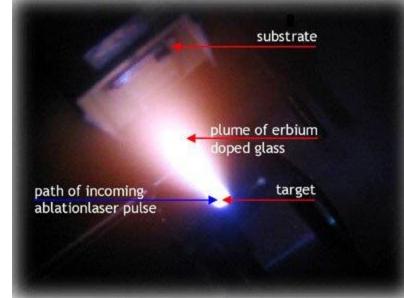
Stoichiometric mass transfer by ablation of a solid target using a

pulsed laser in HV or UHV.

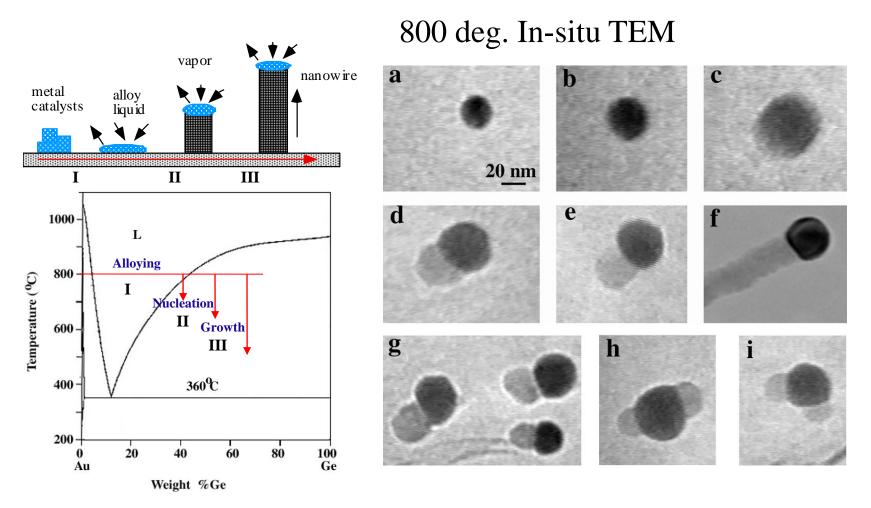


good for materials of complex stoichiometry



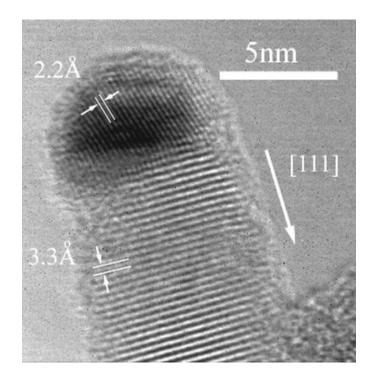


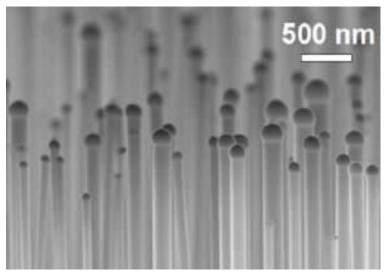
Vapor-Liquid-Solid Nanowire Growth

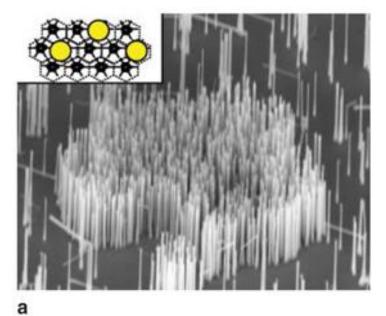


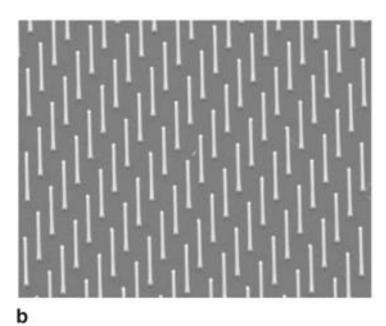
Unidirectional growth is the consequence of an anisotropy in solid-liquid interfacial energy.

Y. Wu et al. J. Am. Chem. Soc. 2001, 123, 3165







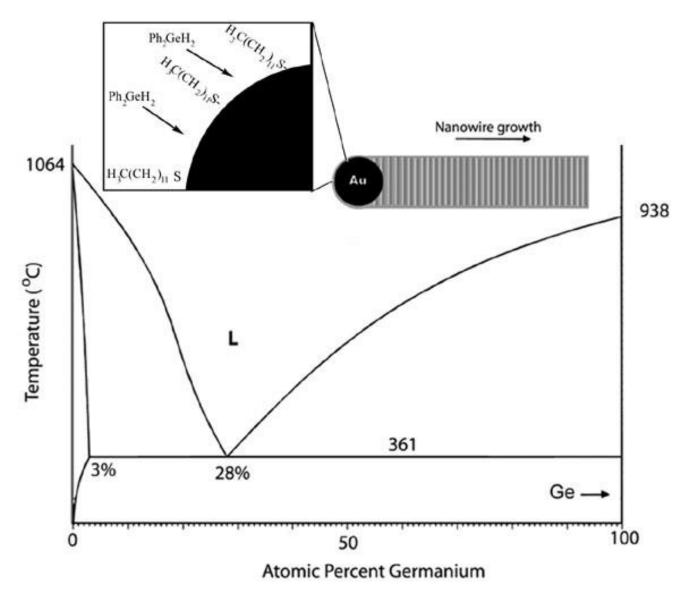


Nanowires grown by PLD

Table 1. Summary of single crystal nanowires synthesized. The growth temperatures correspond to ranges explored in these studies. The minimum and average nanowire diameters were determined from TEM and FE-SEM images. Structures were determined using electron diffraction and lattice resolved TEM imaging: ZB, zinc blende; W, wurtzite; and D, diamond structure types. Compositions were determined from EDX measurements made on individual nanowires. All of the nanowires were synthesized using Au as the catalyst, except GaAs, for which Ag and Cu were also used. The GaAs nanowires obtained with Ag and Cu catalysts have the same size distribution, structure, and composition as those obtained with the Au catalyst.

Material	Growth Temperature [°C]	Minimum Diameter [nm]	Average Diameter [nm]	Structure	Growth Direction	Ratio of Components
GaAs	800-1030	3	19	ZB	<111>	1.00:0.97
GaP	870-900	3-5	26	ZB	<111>	1.00:0.98
GaAs _{0.6} P _{0.4}	800-900	4	18	ZB	<111>	1.00:0.58:0.41
InP	790-830	3-5	25	ZB	<111>	1.00:0.98
InAs	700-800	3-5	11	ZB	<111>	1.00:1.19
InAs _{0.5} P _{0.5}	780-900	3-5	20	ZB	<111>	1.00:0.51:0.51
ZnS	990-1050	4-6	30	ZB	<111>	1.00:1.08
ZnSe	900-950	3-5	19	ZB	<111>	1.00:1.01
CdS	790-870	3-5	20	W	<100>, <002>	1.00:1.04
CdSe	680-1000	3-5	16	W	<110>	1.00:0.99
Si _{1-x} Ge _x	820-1150	3-5	18	D	<111>	Si, Ge,

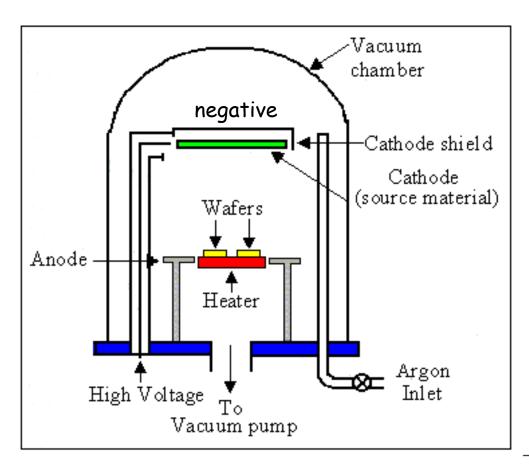
Solution-liquid-solid (SLS) nanowire growth



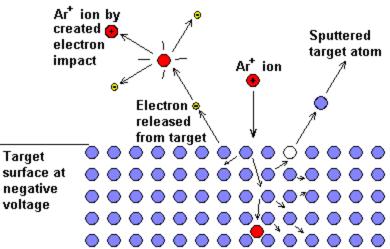
Korgel Group, UT, Austin, Department of Chemical Engineering

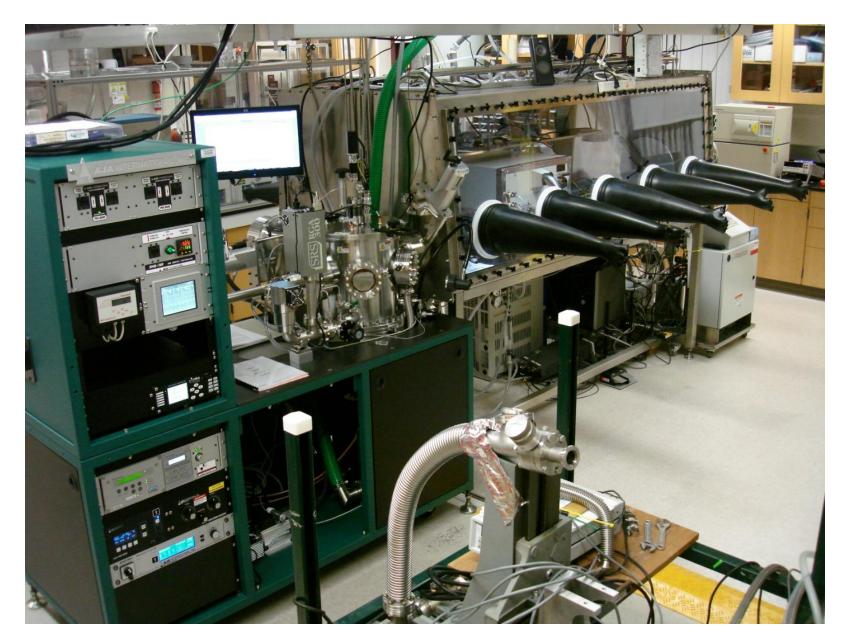
SPUTTERING

Bombardment of high-energy ions (usually argon) ejects atoms from a negatively-charged source to create a thin film coating.

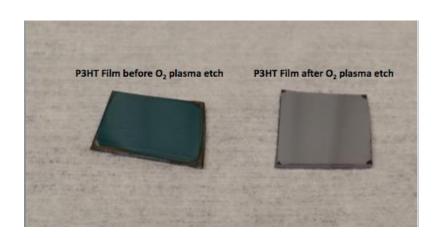


- vacuum (10⁻⁷ T),
 line-of-sight method
- argon ions created by high voltage dc or rf plasma
- produces hard, dense coatings











MOLECULAR BEAM EPITAXY (MBE)

UHV technique for producing very high quality epitaxial layers with monolayer thickness control.

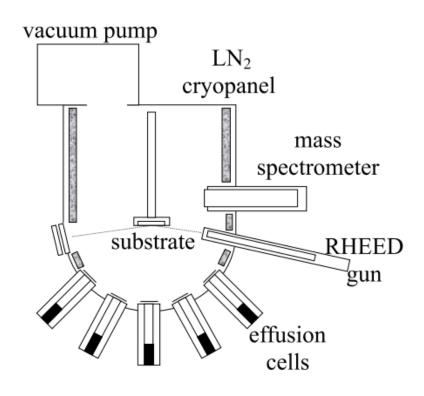
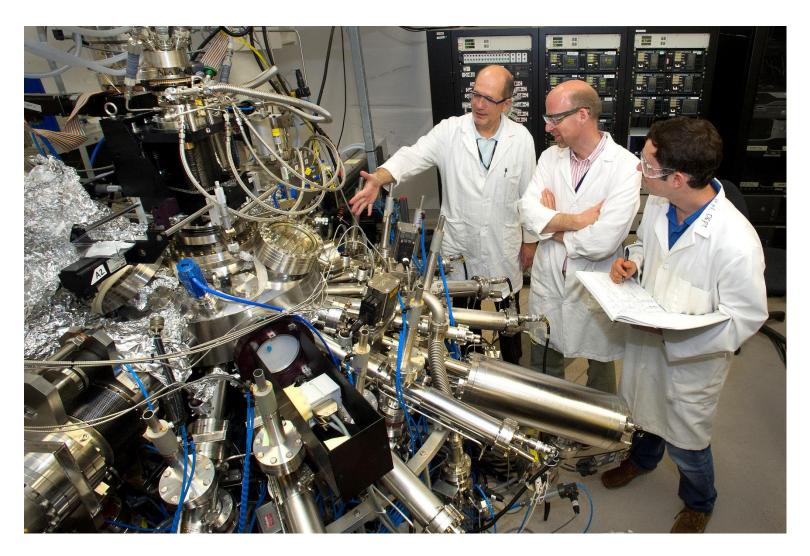


Fig. 1: A typical MBE system.

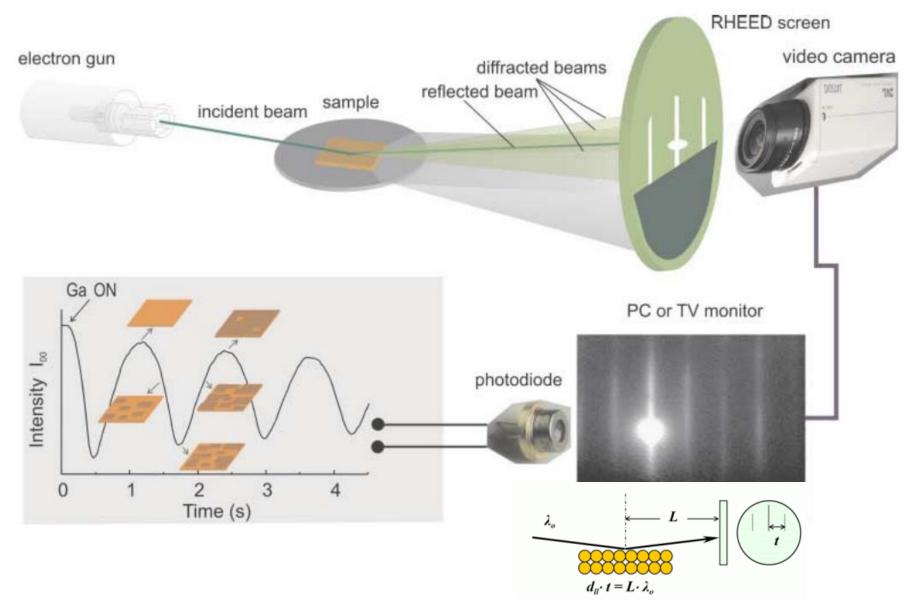
- ultrahigh vacuum (10⁻¹⁰ Torr), medium temp, line-of-sight method
- UHV gives long mean free path

 → "molecular beams" and
 ultrapure crystals
- slow growth rate (1 ML s⁻¹)
 promotes extremely high quality
 crystals
- very expensive



Brookhaven Nat'l Lab

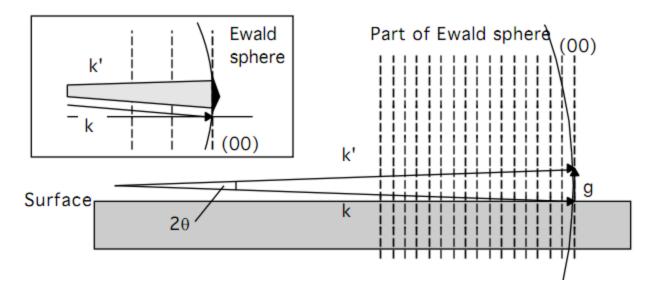
Reflection high-energy electron diffraction (RHEED)



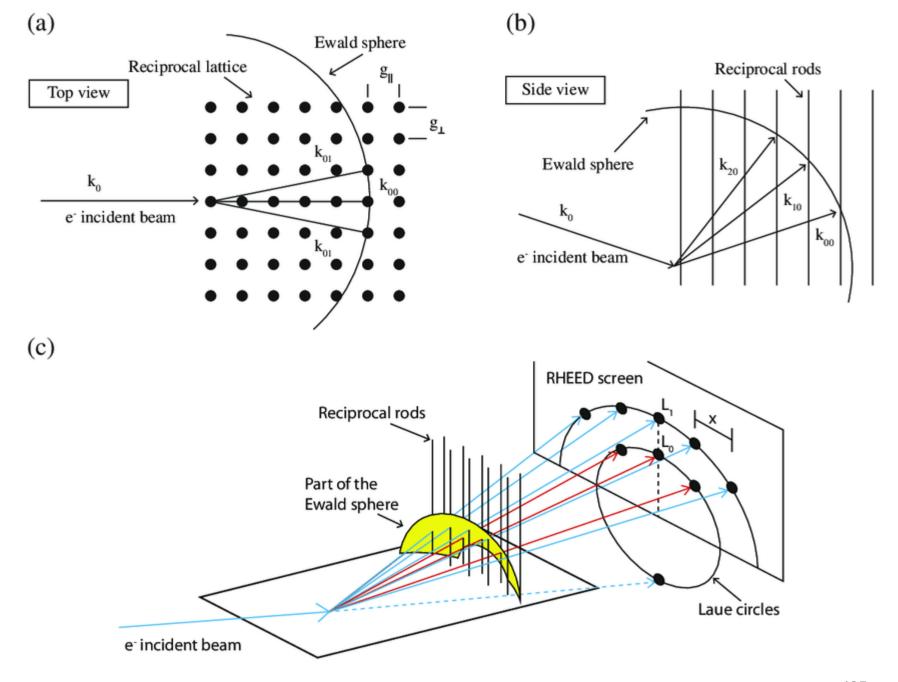
3-100 keV electrons used to monitor monolayer growth

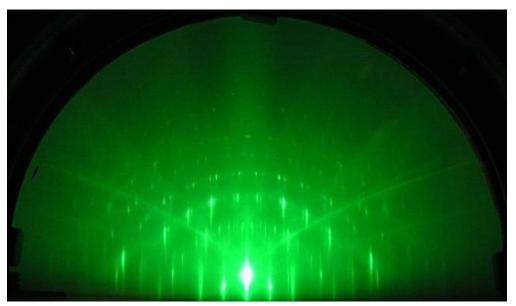
wave vector of 50 keV electron ~120 Å⁻¹ → large Ewald sphere no diffraction condition in 3rd dimension → reciprocal lattice rods

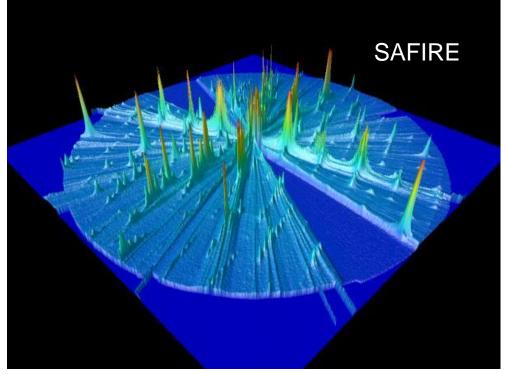
Draw Ewald sphere for an incidence angle of 88°:



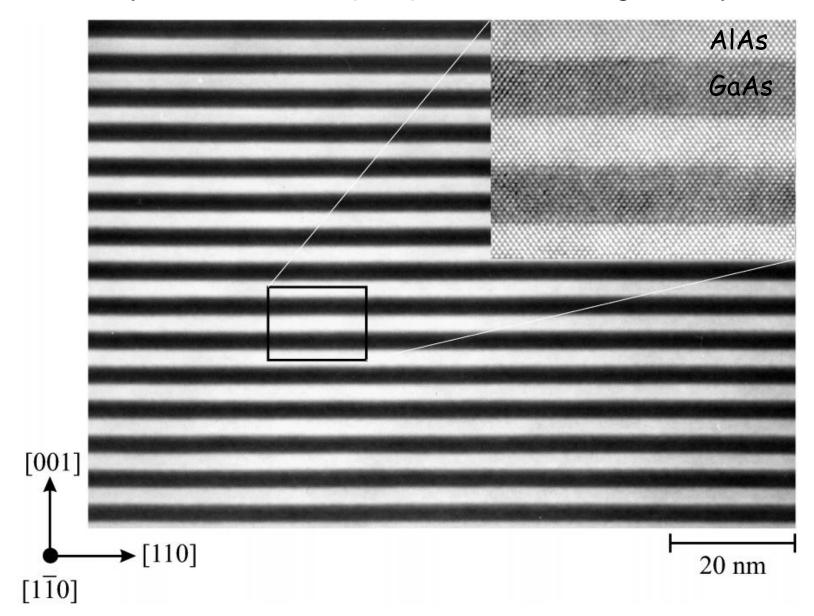
- Ewald sphere crosses many lattice rods, resulting in many spots separated by small diffraction angle differences. However, few of these are close to the grazing exit angles, so only a few spots are seen on the RHEED screen.
- The crossing of Ewald sphere with lattice rod can be very poorly defined → RHEED spots are broadened into vertical streaks







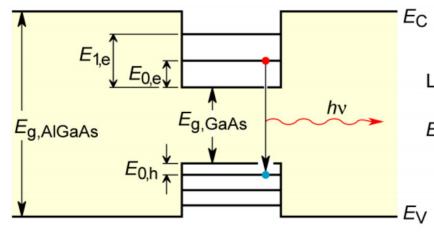
SC multilayer stack – "multiple quantum well" – grown by MBE



QUANTUM WELLS

GaAs QWs

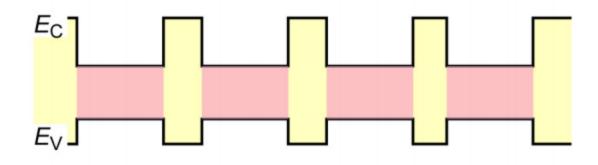
A finite potential well with only discrete energy levels.

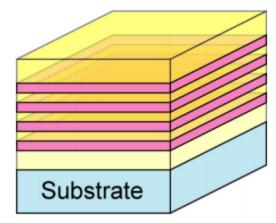


Lowest transition energy:

$$E = hv$$

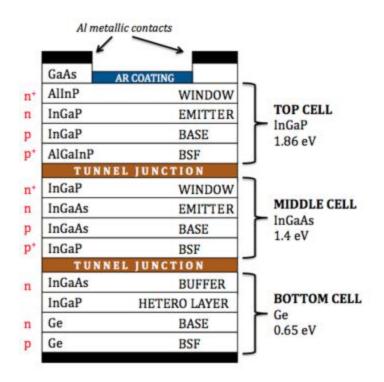
= $E_{g,GaAs} + E_{0,e} + E_{0,h}$

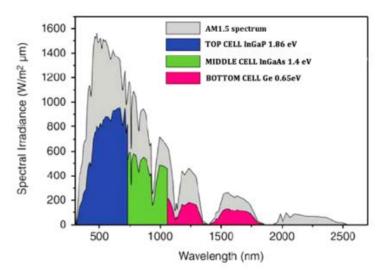


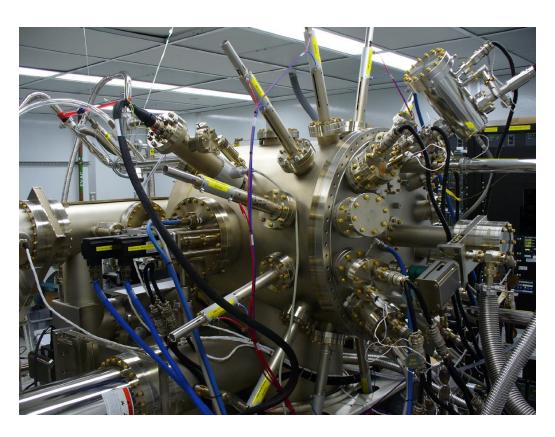


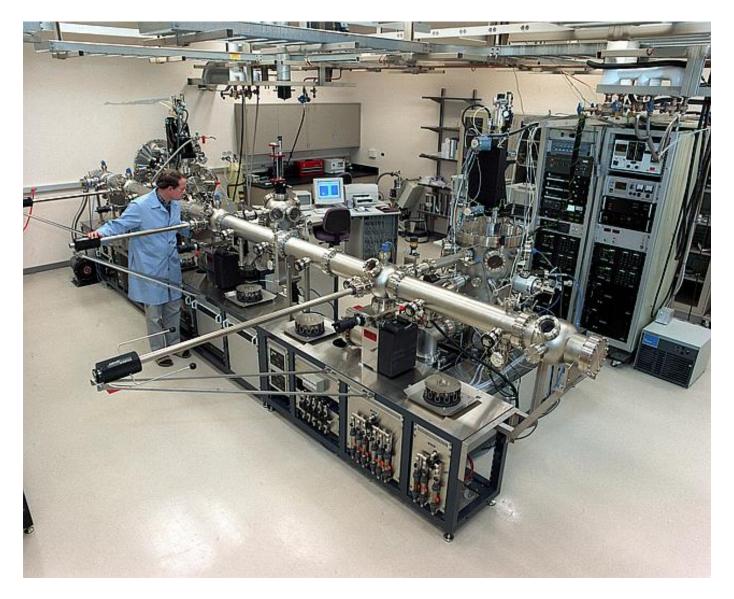
- can design transition energies
- high radiative efficiency
- low laser thresholds
- low surface recombination

MULTIJUNCTION SOLAR CELLS





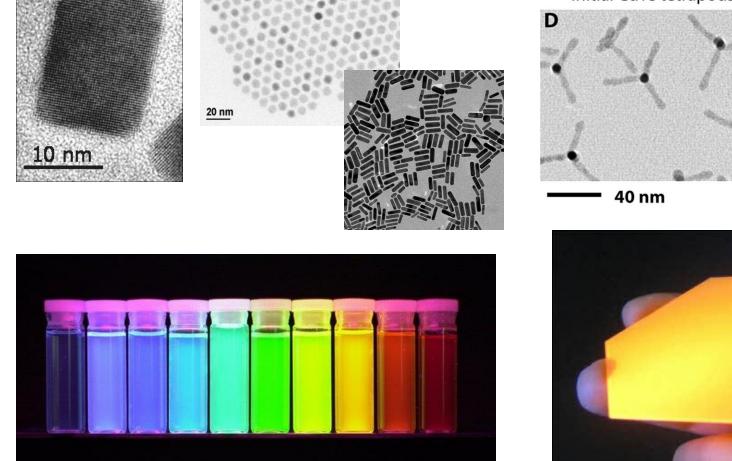


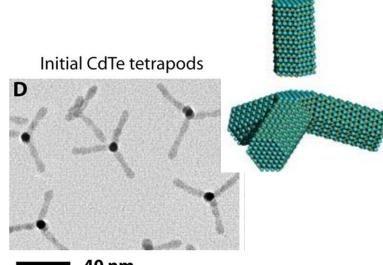


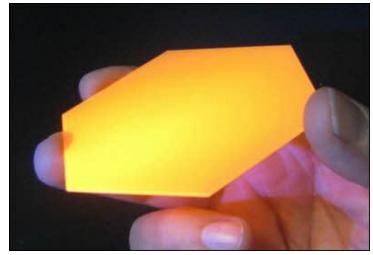
William R. Wiley Environmental Molecular Sciences Laboratory (PNNL)

SEMICONDUCTOR QUANTUM DOTS

Nanometer size crystals with size-dependent properties.



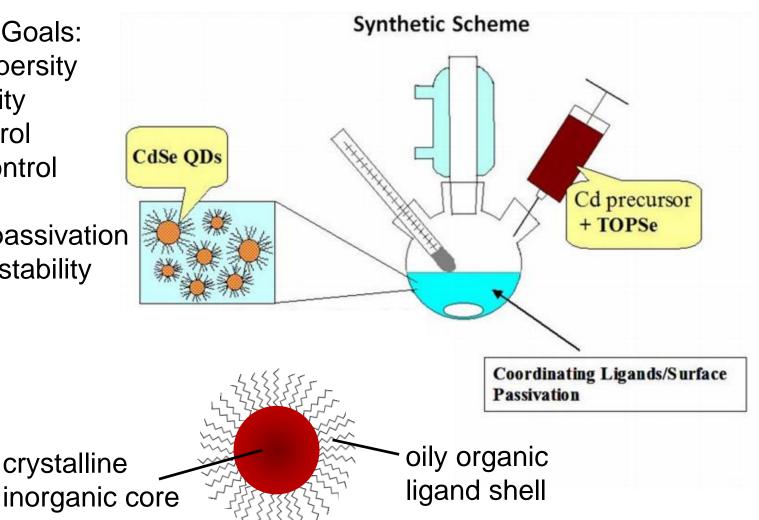




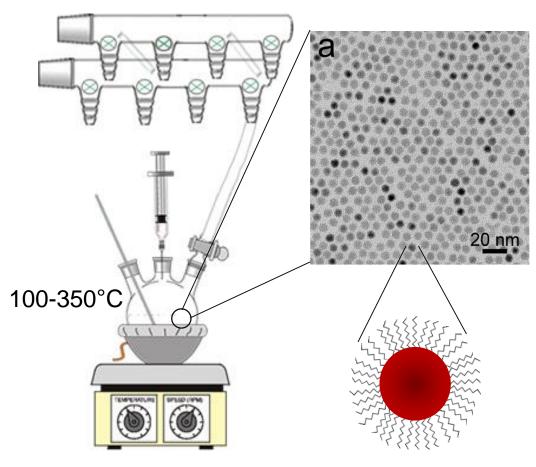
Synthesis of colloidal QDs

Synthesis Goals:

- monodispersity
- crystallinity
- size control
- shape control
- doping
- surface passivation
- colloidal stability



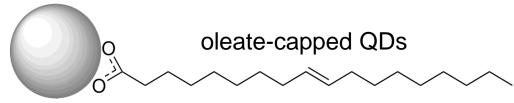
COLLOIDAL SC QUANTUM DOTS



for PbSe quantum dots

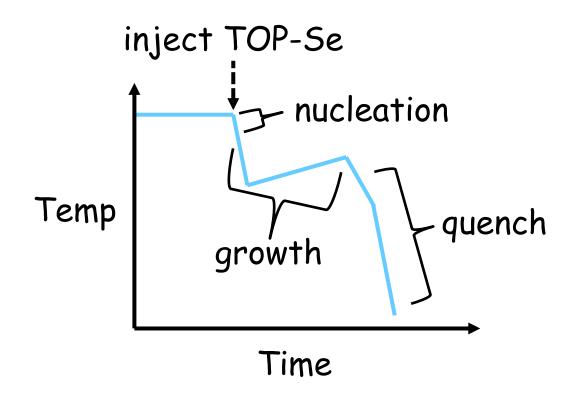
 $PbO + 2OA \rightarrow Pb(OA)_2 + H_2O$

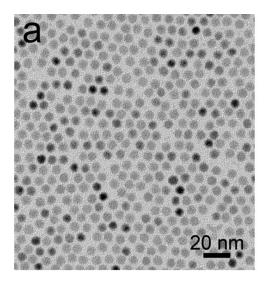
 $Pb(OA)_2 + TOP-Se \rightarrow PbSe + by-products$



Hot injection method

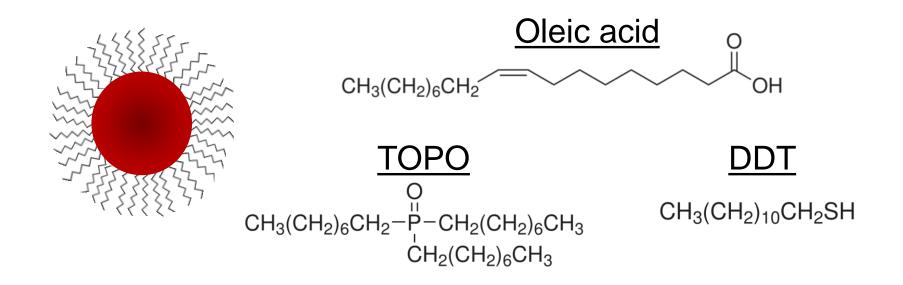
$$Pb(OA)_2 + (C_8H_{17})_3PSe \xrightarrow{ODE} PbSe dots$$





5% polydispersity (unit cell roughness)

Native surface ligands



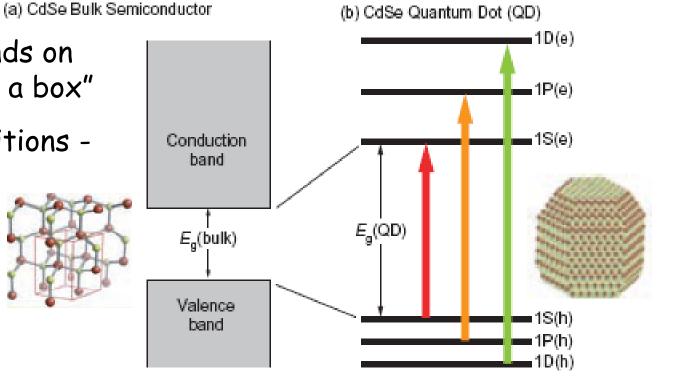
Functions:

- control size and shape
- prevent aggregation
- passivate surface states → strong PL
- doping?
- isolate QD from its environment (chemical stability)

QUANTUM CONFINEMENT

energy gap depends on size - "particle in a box"

discrete e transitions - "artificial atoms"

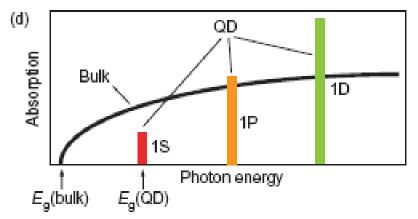


(c)
$$E_{g}(QD) \approx E_{g0} + \frac{\hbar^{2}\pi^{2}}{2m_{eh}R^{2}}$$

$$m_{eh} = \frac{m_{e}m_{h}}{m_{e} + m_{h}}$$

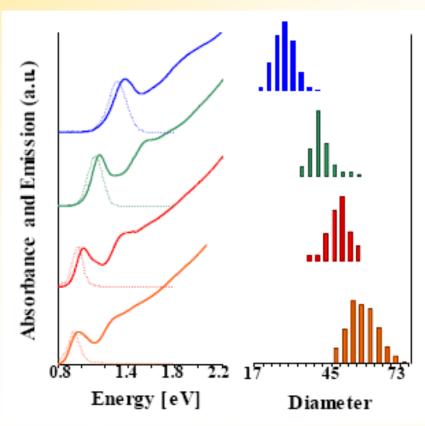
 $m_{\rm e}=\,$ effective electron mass

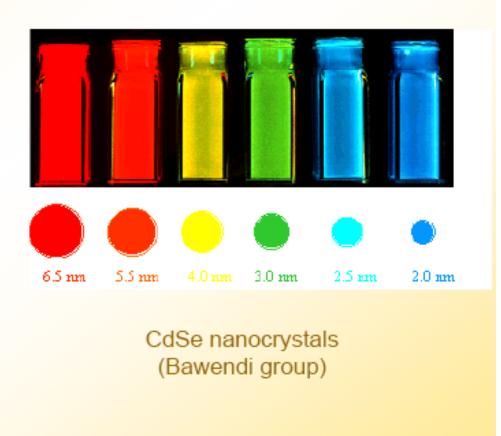
m_h = effective hole mass



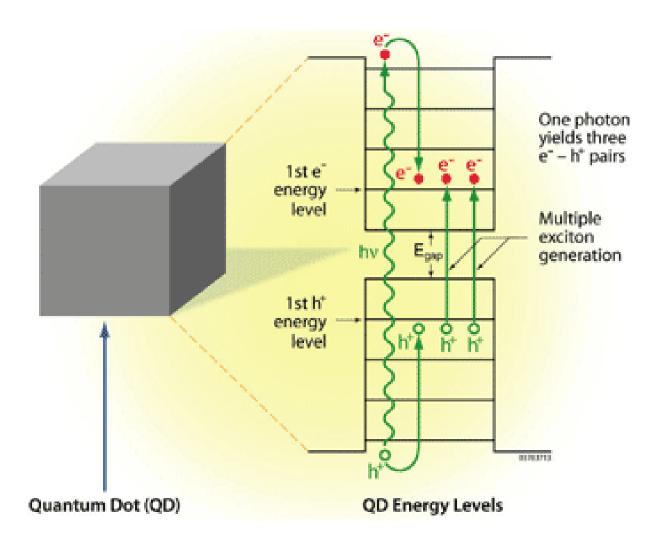
smaller dots \rightarrow larger bandgap \rightarrow bluer absorption & emission

InAs nanocrystals (Banin group)





MULTIPLE EXCITON GENERATION



larger currents for solar cells

NUCLEATION

Nucleation = localized creation of a distinct thermodynamic phase.

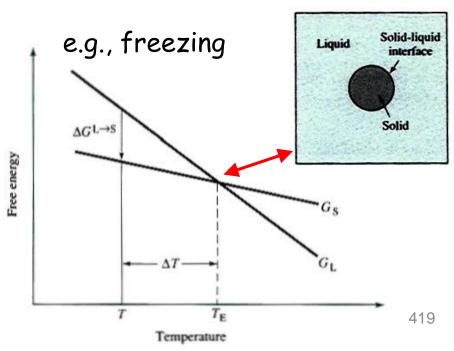
simple examples: liquid in gas, solid in liquid, solid in gas, ZB in WZ

heterogeneous nucleation: nucleation assisted by a nucleation site, usually a surface (e.g., substrate, suspended particle, dust, etc.)

homogeneous nucleation: nucleation without a nucleation site. Harder to achieve than heterogeneous nucleation.

The driving force for nucleation is the lowering of free energy.

$$\Delta G = \Delta H - T \Delta S$$



SUPERCOOLING

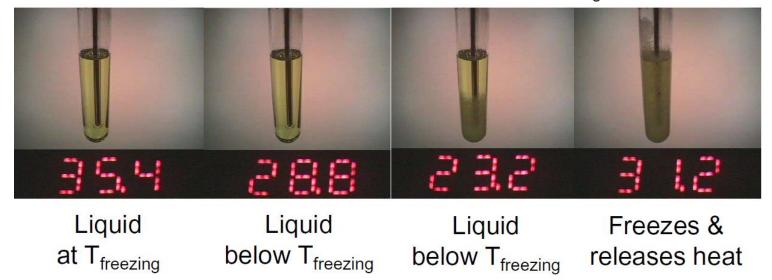
Nucleation and Growth

supersaturation energetics kinetics

Liquids are supposed to freeze when cooled to the freezing point

However, many liquids remain liquid below the freezing point because the freezing process is exceptionally slow

Example: 1-chlorine-2-nitrobenzene with $T_{freezing} = 35.4$ °C

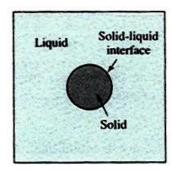


Freezing of supercooled liquids is *thermodynamically favored* but *kinetically hindered*

NUCLEATION and **GROWTH**

consider a spherical amorphous solid nucleating from a homogeneous supersaturated liquid:

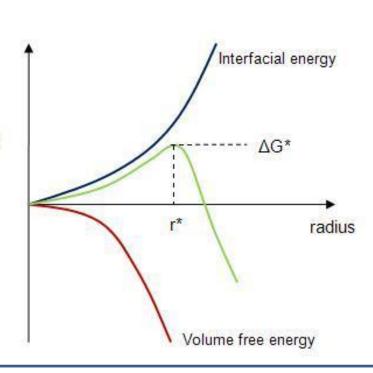
ΔG



$$G_v$$
 = volume free energy σ = interfacial free energy

$$\Delta G(r) = \frac{4}{3}\pi\Delta G_v r^3 + 4\pi\sigma r^2$$
 energy liberated by forming volume (-)

energy required to form interface (+)



critical nucleus r*:
$$r^* = -\frac{2\sigma}{\Delta G_v}$$

r<r* - nucleus dissolves r>r* - nucleus grows

OSTWALD RIPENING

Initially the solid particles draw their material from the solution/melt. Later, as the solution/melt becomes depleted, the particles compete with each other for growth. In Ostwald ripening, small particles shrink and supply atoms to larger particles, which grow.



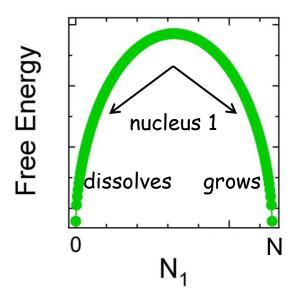
thermodynamically driven - atoms on surface are less stable than atoms in the bulk b/c lower coordination number (poorer bonding), so system can lower energy by reducing surface area.

OSTWALD RIPENING

consider two spherical nuclei w/N_1 and $N-N_1$ atoms (N constant):

with $\Omega \equiv$ atomic volume,

$$G(N_1, N - N_1) = N\Omega G_v + 4\pi\sigma \left(\frac{3\Omega}{4\pi}\right)^{2/3} \left[N_1^{2/3} + (N - N_1)^{2/3}\right]$$

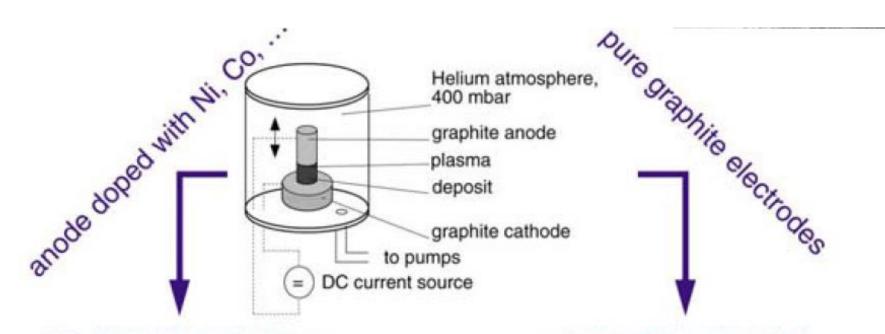


minimum G occurs when the two equal spheres combine into one big sphere: $(30)^{2/3}$

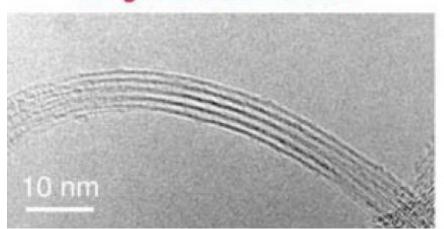
 $\Delta G = -4\pi\sigma \left(\frac{3\Omega}{4\pi}\right)^{2/3} (2^{1/3} - 1)N^{2/3}$

423

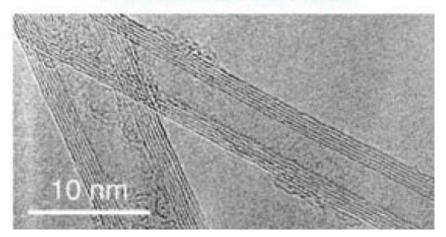
CARBON NANOTUBES: ARC DISCHARGE



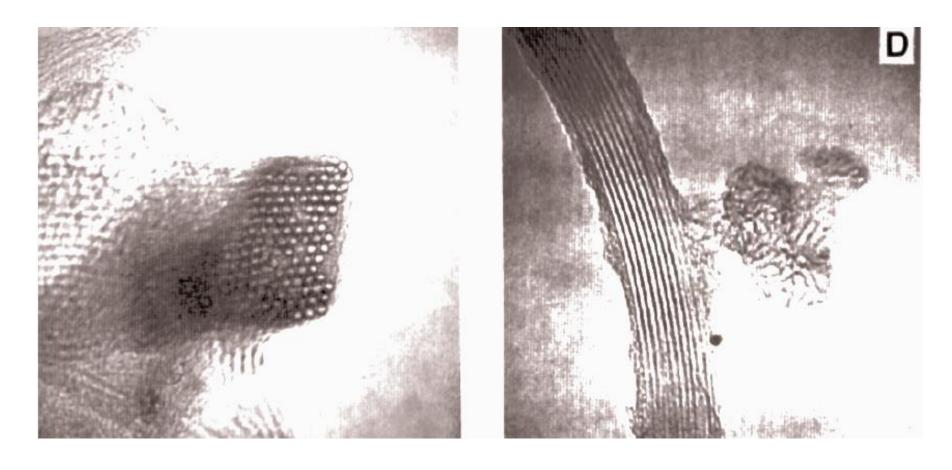
Single wall nanotubes



Multiwall nanotubes

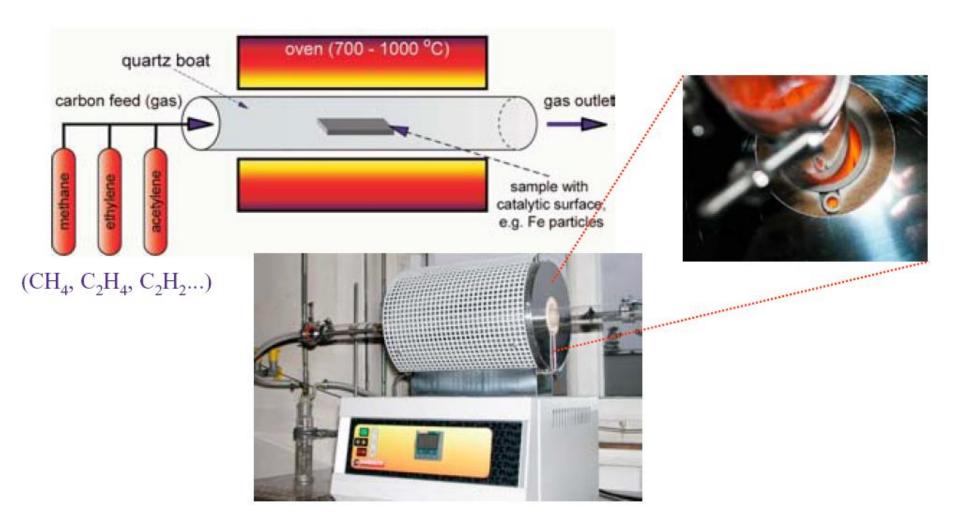


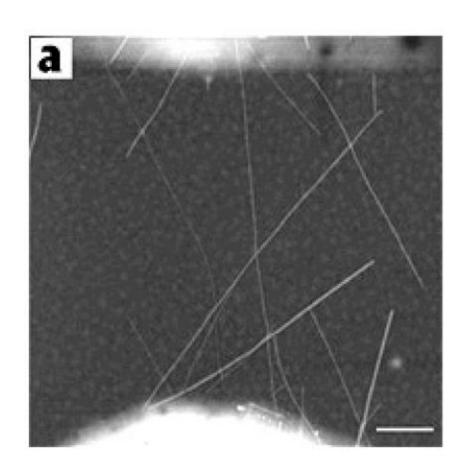
LASER ABLATION of CNTs



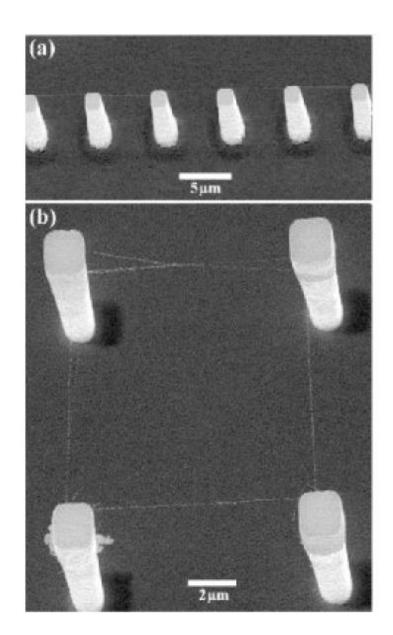
Thess et al., Science 273, 483 (1996)

CVD of **CNTs**

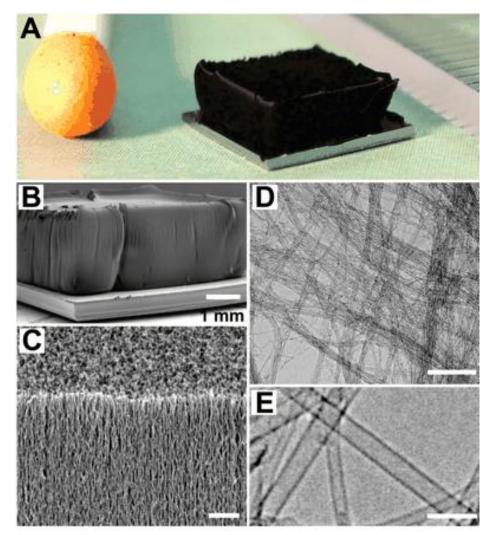




from the DaiLab @ Stanford

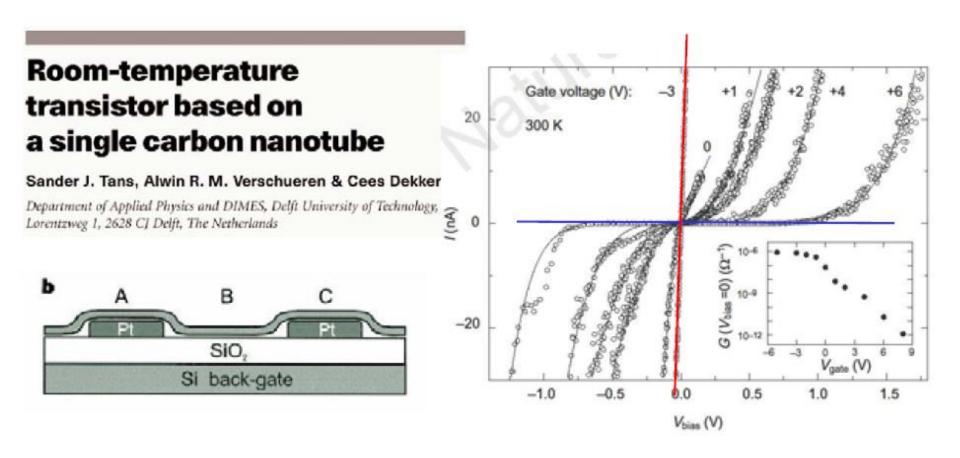


Water-Assisted Highly Efficient Synthesis of Impurity-Free Single-Walled Carbon Nanotubes



Science 19 November 2004: Vol. 306. no. 5700, pp. 1362 - 1364

CNT DEVICES: FIELD EFFECT TRANSISTOR



p-type behaviour!

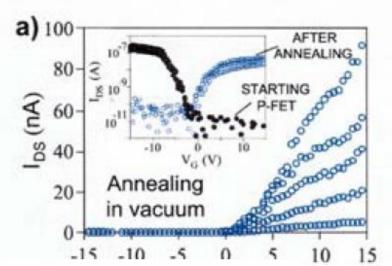
CNT-BASED LOGIC

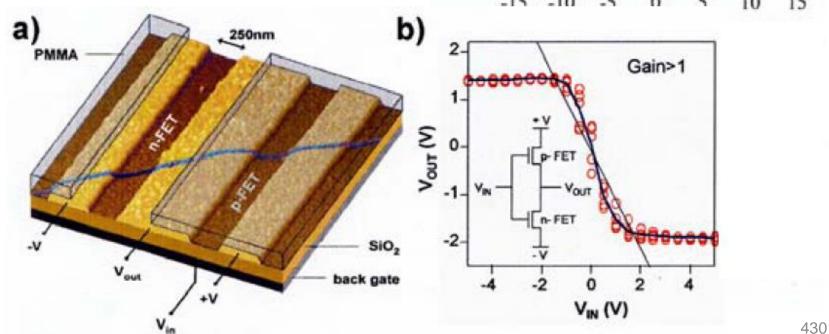
Carbon Nanotube Inter- and Intramolecular Logic Gates

V. Derycke, R. Martel, J. Appenzeller, and Ph. Avouris*

IBM Research Division, T. J. Watson Research Center, Yorktown Heights, New York 10598

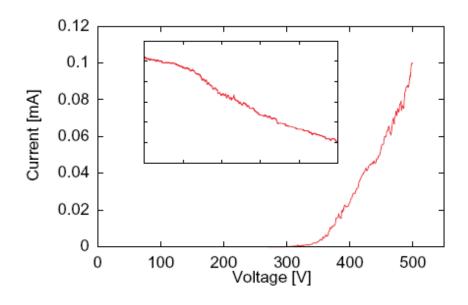
complementary logic based CNT inverter

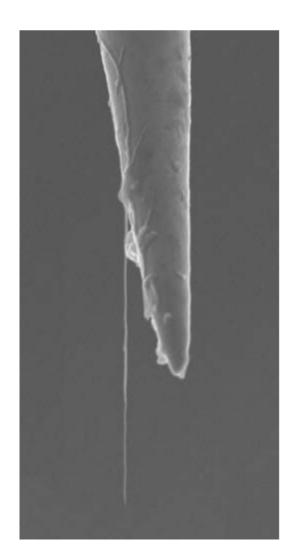


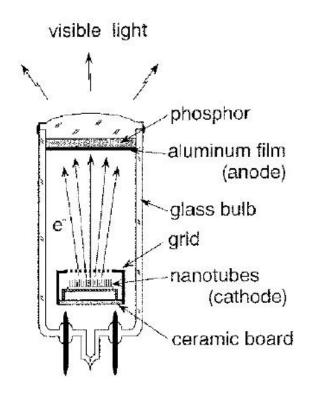


CNT FIELD EMITTERS

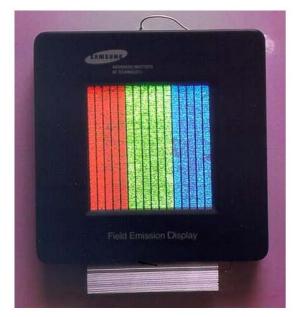
- low voltage (100V @ 1mm)
- high currents (0.2 mA)
- stable emission











SONY

Samsung

Motorola ...